Sheet 1 of 2 Form 1449* Atty. Docket No.: 303.444US5 Serial No. Unknown INFORMATION DISCLOSURE STATEMENT Applicant: Scott G. Meikle et al. BY APPLICANT Filing Date: Herewith (Use several sheets if necessary) Group: Unknown U.S. PATENT DOCUMENTS **Examiner Initial Document Number Filing Dat Date Name Class Subclass 4,238,872 12/16/1980 Akashi 24 205.11F 4,774,201 09/01/1988 Woo, et al. 437 41 4,823,182 04/18/1989 Okumura 357 67 4,847,111 07/11/1989 Chow, Y.C., et al. 427 38 06/30/88 4,884,123 11/28/1989 Dixit, P., et al. 357 71 02/19/87 4,923,715 05/08/1990 Matsuda, T., et al. 427 237 05/30/89 4,960,732 10/02/1990 Dixit, et al. 437 192 4,974,056 11/27/1990 Brodsky, et al. 357 71 5,124,780 06/23/1992 Sandhu, G.S., et al. 357 67 06/10/91 5,132,756 07/01/1992 Matsuda 257 763 5,150,276 09/22/1992 Gonzalez, F., et al. 361 303 01/24/92 5,168,073 12/01/1992 Gonzalez, F., et al. 437 47 5,187,557 Zenke, M. 02/16/1993 257 310 11/15/90 5,192,703 Lee, R.R., et al. 03/09/1993 437 52 10/31/91 5,227,323 07/01/1993 Nishitsuji, et al. 437 47 5,238,872 08/24/1993 Thalapaneni, G., et al. 437 176 07/01/92 5,290,609 03/01/1994 Horiike, Y., et al. 427 576 03/09/92 5,336,638 Suzuki, M., et al. 08/09/1994 437 190 03/06/92 5,341,015 Prall, et al. Prall, K.D., et al. 08/23/1994 257 412 5,341,016 08/23/1994 257 412 06/16/93 5,487,923 01/30/1996 Min, S., et al. 427 11/23/93 569 5,691,235 11/25/1997 Meikle, S., et al. Sasaki, K., et al. 437 190 06/12/96 5,861,675 01/19/1999 257 764 12/22/97 5,888,588 03/30/1999 Nagabushmnam, R., et al.427 248.1 03/31/97 FOREIGN PATENT DOCUMENTS **Examiner Document Number Date Country Class Subclass 02-177427 07/01/1990 Japan 05-129231 05/25/1993 Japan H01L 21/285 05-236282 09/03/1993 Japan H01L 21/285 6-275776 -09/30/1994 Japan HO1L 27/04 60-193333 . 10/01/1985 Japan OTHER DOCUMENTS **Examiner Initial

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JRE STATEMENT Applicant: Scott G. Meikle et al.

Group: Unknown

(Use several sheets if necessary)

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